

MBE Lab #1

Oxide MBE of Binary Oxides
(SnO , MgO , Dy_2O_3
depending on your group)

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Questions for MBE Lab #1

- Substrate to use (material and orientation)?
- Source material(s) to use?
- Temperature(s) of source material(s)?
- Crucible(s) to contain them?
- Deposition strategy
(codeposition, shuttered growth, etc.)?
- Substrate temperature during growth?
- Oxidant and its pressure during growth?
- How to calibrate growth rate?

Substrate to Use (material and orientation)

- “Substrate Picker” from Materials Project

<https://www.materialsproject.org>

H. Ding, S.S. Dwaraknath, L. Garten, P. Ndione, D. Ginley, and K.A. Persson, “Computational Approach for Epitaxial Polymorph Stabilization through Substrate Selection,” *ACS Applied Materials and Interfaces* **8** (2016) 13086–13093.

Source Material(s) to Use

- Vapor Pressure of the Elements

R.E. Honig and D.A. Kramer, “Vapor Pressure Data for the Solid and Liquid Elements,” *RCA Review* **30** (1969) 285–305.

- Vapor Pressures of Oxides

R.H. Lamoreaux, D.L. Hildenbrand, and L. Brewer, “High-Temperature Vaporization Behavior of Oxides II. Oxides of Be, Mg, Ca, Sr, Ba, B, Al, Ga, In, Tl, Si, Ge, Sn, Pb, Zn, Cd, and Hg,” *Journal of Physical and Chemical Reference Data* **16** (1987) 419–443.

- “Material Deposition Chart” from Kurt J. Lesker Co.

https://www.lesker.com/newweb/deposition_materials/materialdepositionchart.cfm?pgid=0

Source Temperature(s)

- Vapor Pressure of the Elements

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- Vapor Pressures of Oxides

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Crucible(s)

- “Material Deposition Chart” from Kurt J. Lesker Co.

https://www.lesker.com/newweb/deposition_materials/materialdepositionchart.cfm?pgid=0

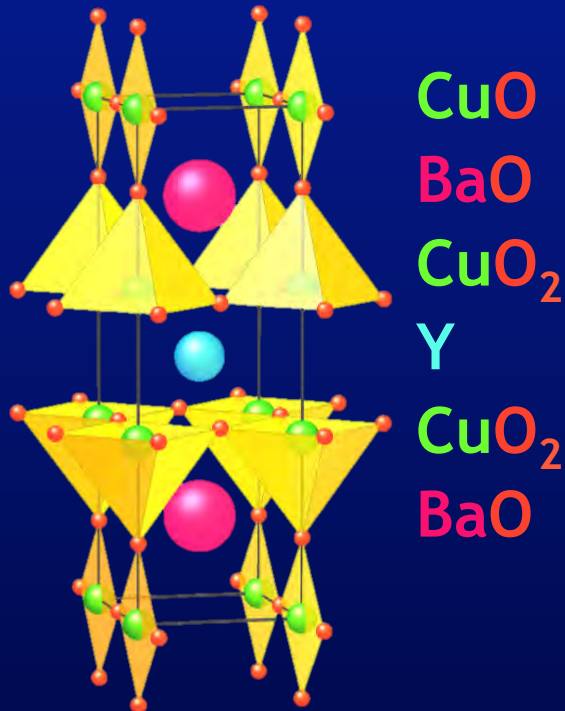
- Phase Diagrams

Desk Handbook: Phase Diagrams for Binary Alloys,
edited by H. Okamoto (ASM International, 2000).

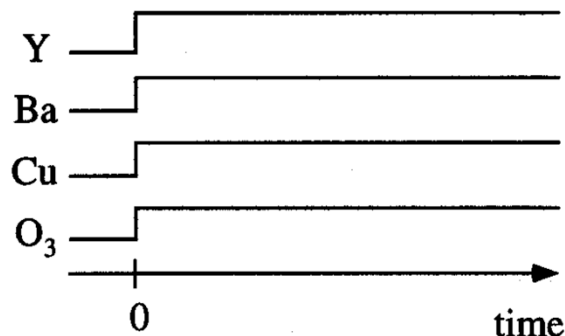
ACerS—NIST Phase Equilibria Diagrams On-Line

Deposition Strategy (codeposition, shuttered growth, etc.)

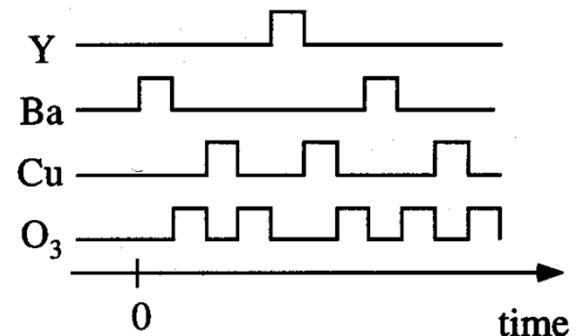
- This is the fun and freedom of MBE!



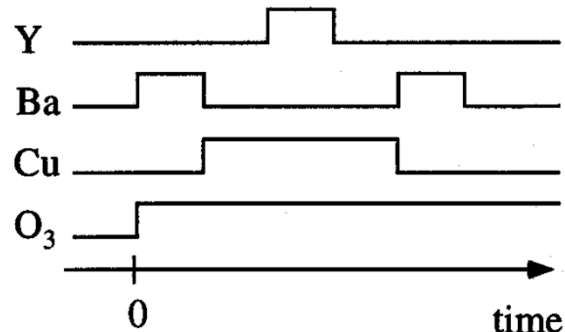
Codeposition



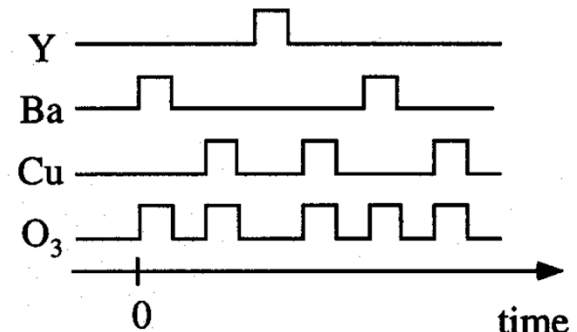
Layer-by-Layer, Including Oxidation



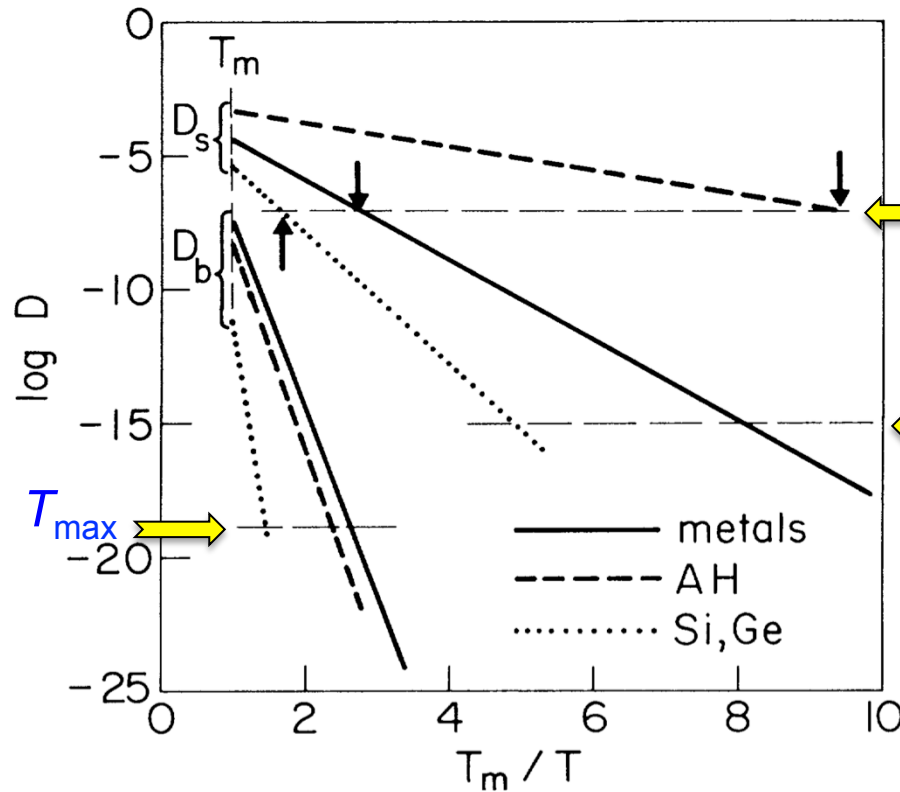
Partial Codeposition



Layer-by-Layer with Interruptions



Substrate Temperature



Assuming growth rate of
0.1 monolayer/sec

T_{\min} for smooth epitaxial films
(growth by step propagation)

T_{\min} for epitaxy

Optimal Growth Temperatures

$$0.55 < \frac{T_{\text{sub}}}{T_{\text{melt}}} < 0.7 \text{ for semiconductors}$$

$$0.35 < \frac{T_{\text{sub}}}{T_{\text{melt}}} < 0.4 \text{ for metals}$$

$$0.1 < \frac{T_{\text{sub}}}{T_{\text{melt}}} < 0.4 \text{ for simple ceramics}$$

M.H. Yang and C.P. Flynn

“Growth of Alkali Halides from Molecular Beams: Global Growth Characteristics”
Physical Review Letters **62** (1989) 2476-2479.

Oxidant and its Pressure

- Ellingham Diagram

I. Barin, Thermochemical Data of Pure Substances, 3rd Ed., Vol. I and Vol. II (VCH, Weinheim, 1995).

- Thermodynamics of MBE (TOMBE) Diagram

H.P. Nair, Y. Liu, J.P. Ruf, N.J. Schreiber, S-L. Shang, D.J. Baek, B.H. Goodge, L.F. Kourkoutis, Z.K. Liu, K.M. Shen, and D.G. Schlom, “Synthesis Science of SrRuO₃ and CaRuO₃ Epitaxial Films with High Residual Resistivity Ratios,” *APL Materials* **6** (2018) 046101.

- If Desire Highest Oxidation State of all cations, then higher activity is better (within the limits of MBE, the equipment, and stable fluxes)

How to Calibrate Growth Rate

- Shadow Mask and Surface Profilometer
- Quartz Crystal Microbalance
- Ion Gauge
- RHEED Oscillations
- Shuttered RHEED Oscillations
- Rutherford Backscattering Spectrometry
- Mass Spectrometer
- Atomic Absorption Spectroscopy
- Atomic Emission Spectroscopy
- X-Ray Reflectivity, Ellipsometry, ...

If your desired flux of Sr is 30% higher than your measured flux or Sr, by how many °C do you need to increase the temperature of the Sr effusion cell to get the desired flux?

MBE \approx Atomic Spray Painting

